

MODEL 1070

NanoClean

Cleans specimens and holders immediately before insertion into an electron microscope; removes existing carbonaceous debris from the specimen and prevents contamination during imaging and analysis.

| Model 1070 NanoClean Specifications | |
|-------------------------------------|---|
| Plasma system | High frequency (13.56 MHz) power amplifier inductively coupled to a quartz and stainless steel plasma chamber |
| | lon energies less than 12 eV as a function of the downstream plasma |
| | Automatic matching network |
| | Compatible with TEM specimen holders for transmission electron microscopes manufactured by: |
| | FEI Company/Philips Electron Optics |
| | Hitachi High Technologies America Inc. |
| | JEOL Ltd. |
| | Carl Zeiss Microscopy |
| Vacuum system | Oil-free turbomolecular drag pump and a multistage diaphragm pump |
| | Vacuum load lock |
| | Ultimate vacuum of 1 x 10^{-6} mbar |
| Chamber | Accepts two specimen holder ports |
| | Chamber lid provides access for bulk objects up to 3.5 in (8.9 cm) diam |
| | Viewport for chamber observation |
| Gas | Three gas inputs |
| | Nominal 10 psi (200 kPa) delivery pressure |

Flow rate is controlled by the embedded module

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|-------------------------------------|--|
| User interface | Programming through a touch screen embedded module |
| | Dedicated recipes for electron microscopy specimen and grid processing |
| | Ability to customize parameters |
| | Process timer for automatic termination |
| Dimensions | 27 in (69 cm) width \times 22 in (56 cm) height \times 23 in (59 cm) depth |
| Weight | 160 lb (73 kg) |
| Power requirements | 100/120/220/240 V AC, single phase, 660 W |
| Warranty | One years |

